

Inducing and Imaging Localized Passivity Breakdown in Aluminum using an AFM Approach

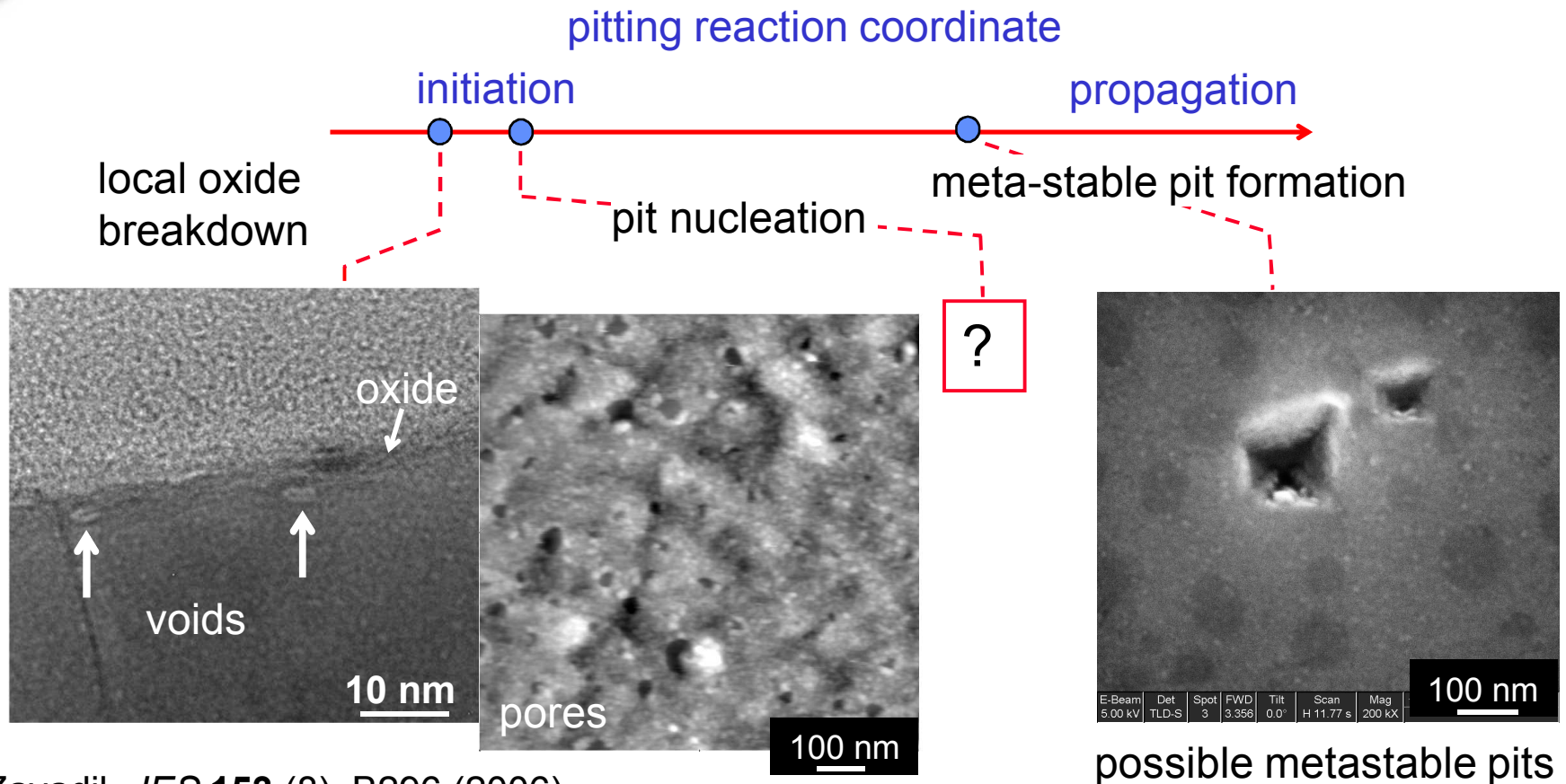
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DOE Basic Energy Sciences Office of Materials & Engineering Sciences

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Our goal is to identify relevant nanostructure and establish causal links with pit initiation



Zavadil, *JES* **153** (8), B296 (2006)

sufficient chemical and physical descriptions do not exist for these entities to support reliability models for high consequence applications of passive metals

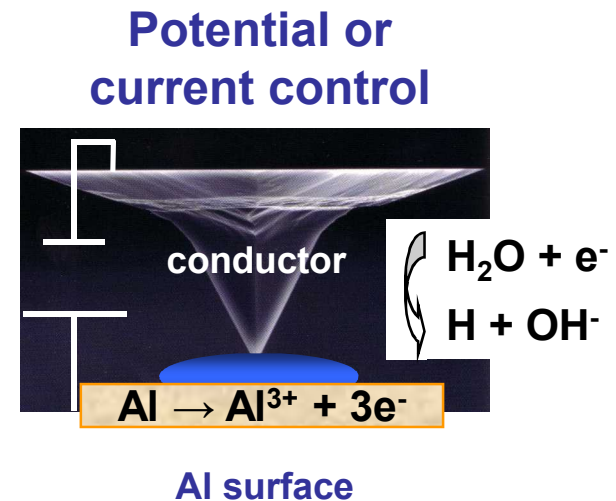
AFM-based approach for inducing local passivity loss

Building from the electrochemical machining field (Schuster & Ertl, Science 2000, Hudson)

- point-and-polarize – short times localize field and constrain location
 μm resolution at 10^1 ns pulses widths
- local current density can be achieved to match metastable pit requirements ($10^4 \text{ A}\cdot\text{cm}^{-2}$)

Proof of concept studies relax the time constraint – msec to sec pulse widths

Operate at 400 nm tip-surface separation



Al thin films are used to facilitate AFM imaging

Type 1:

Al thin films electron beam deposited onto $\text{SiO}_2\text{:Si}$

Nanocrystalline Al(111) textured films are formed - grain dia. 100 to 150 nm

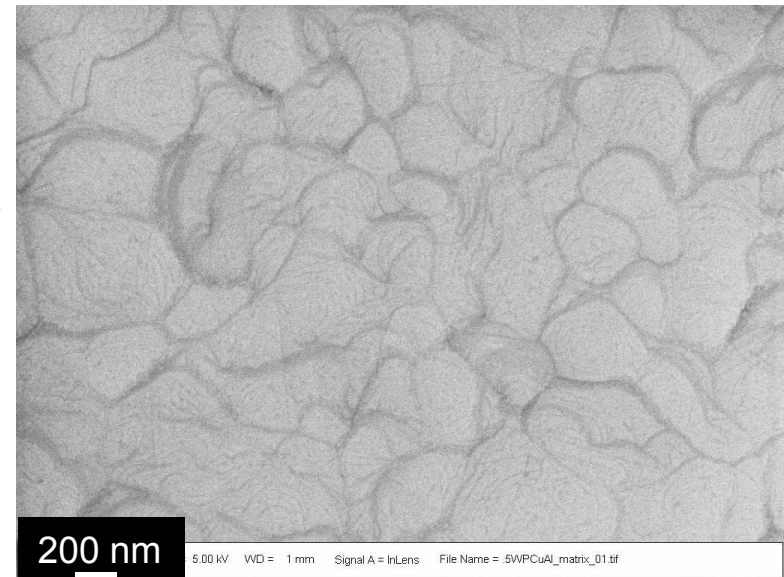
Anhydrous oxides O_2 grown immediately after film deposition

Type 2:

Al-0.5 wt% Cu thin films sputter deposited onto TiN:Ti layer on Si – CMOS interconnect technology

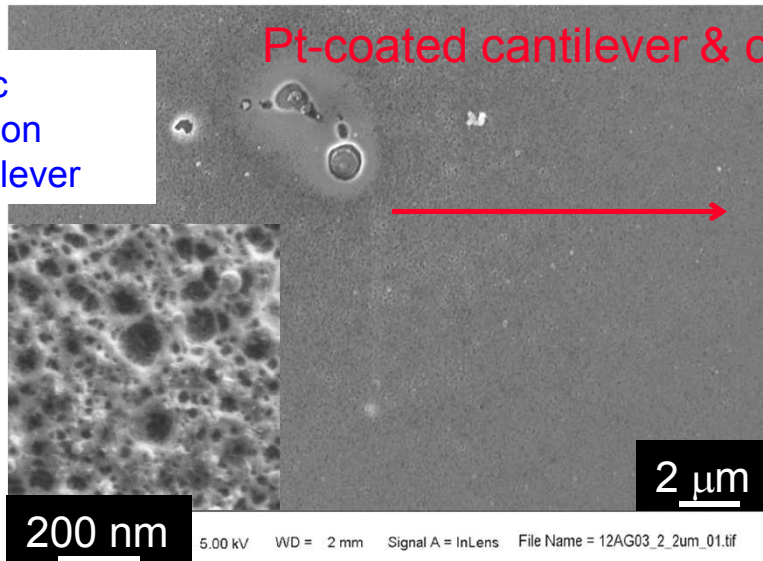
Al(111) texture films are formed - grain dia. 200 to > 500 nm

Air formed oxide at room temperature

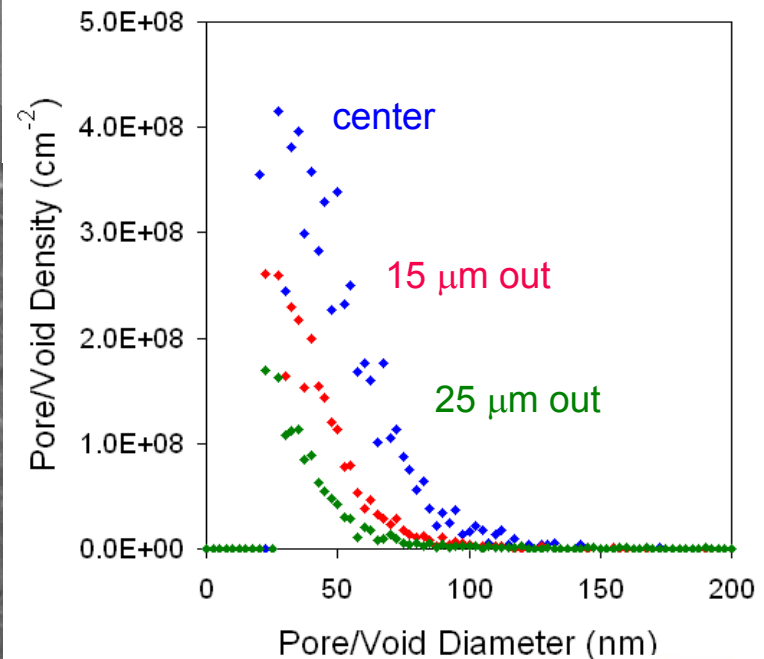
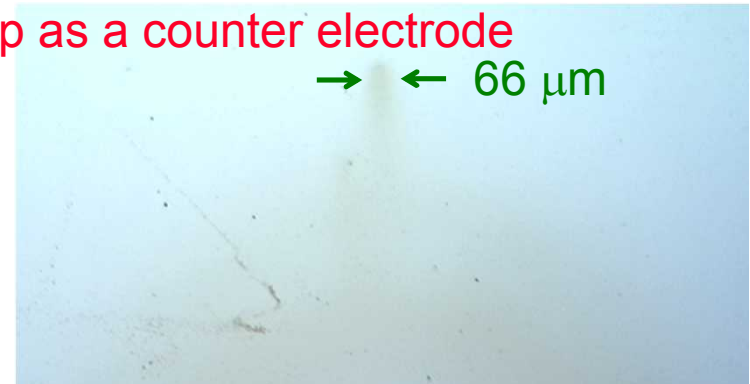
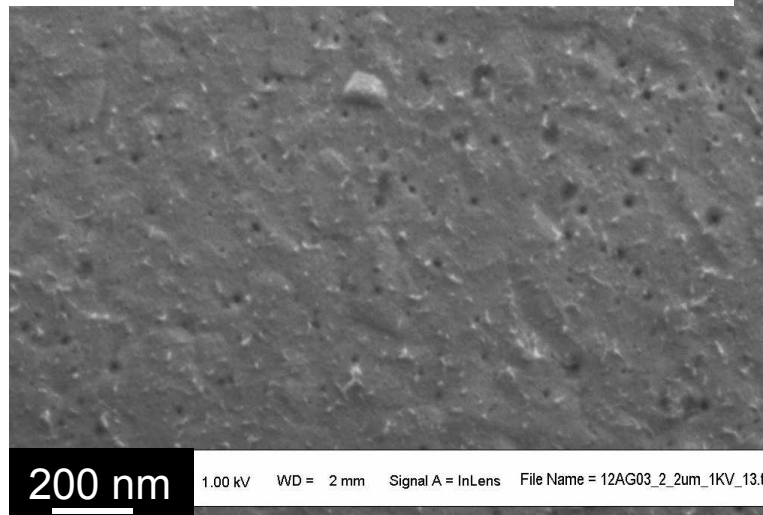


Initial attempts focused on sweeping the potential of the lever & chip to evaluate localization

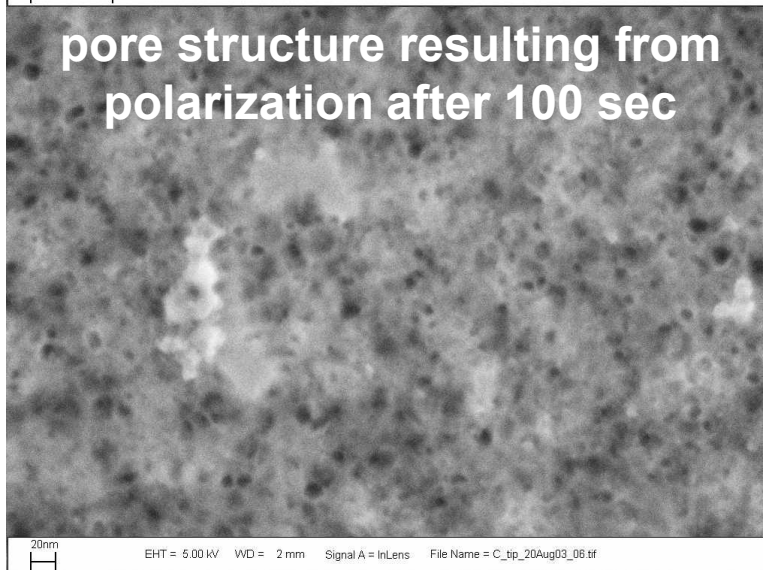
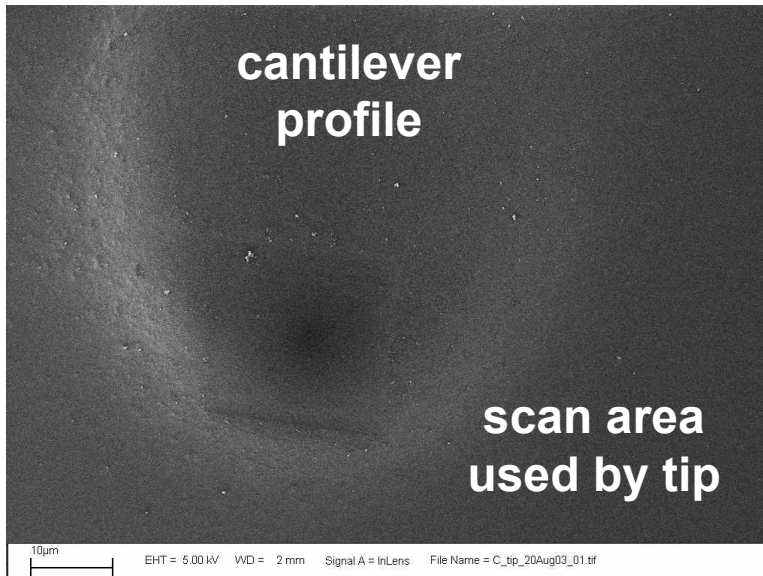
Anodic
oxidation
under lever



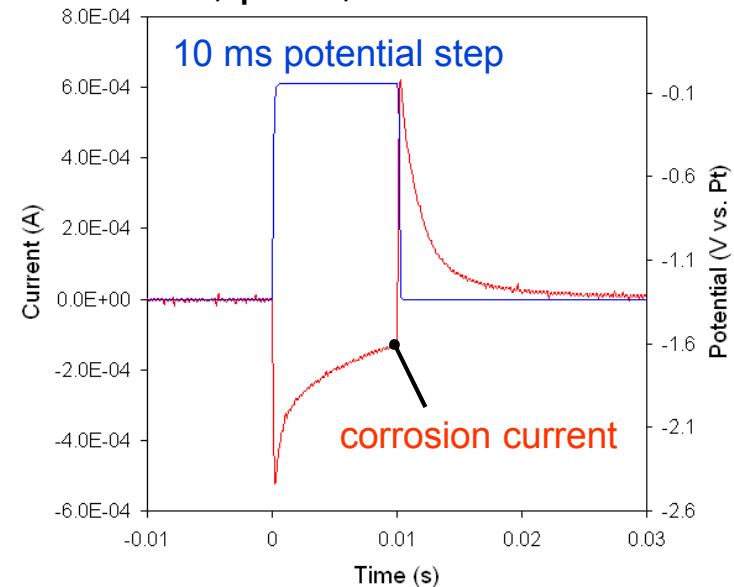
Transition to nano-pores at lever perimeter



Electrical insulation of the chip and holder assembly further improves localized response



50 mM Cl⁻, pH 7, contact mode



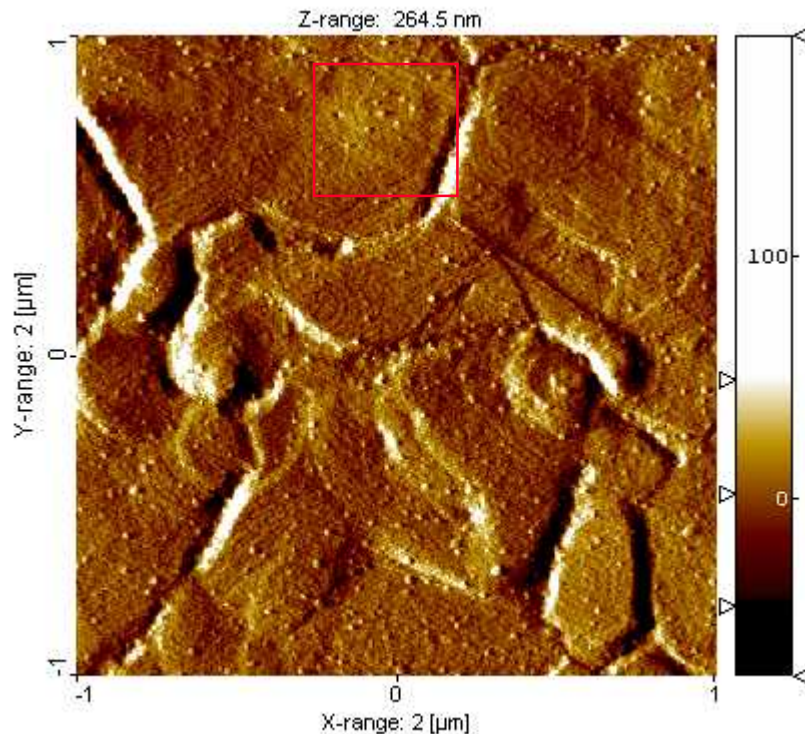
Anodic activity can be localized to the tip and lever perimeter

We do not drive pitting at 0V for pulse times up to 100 sec – consistent with void formation in this system

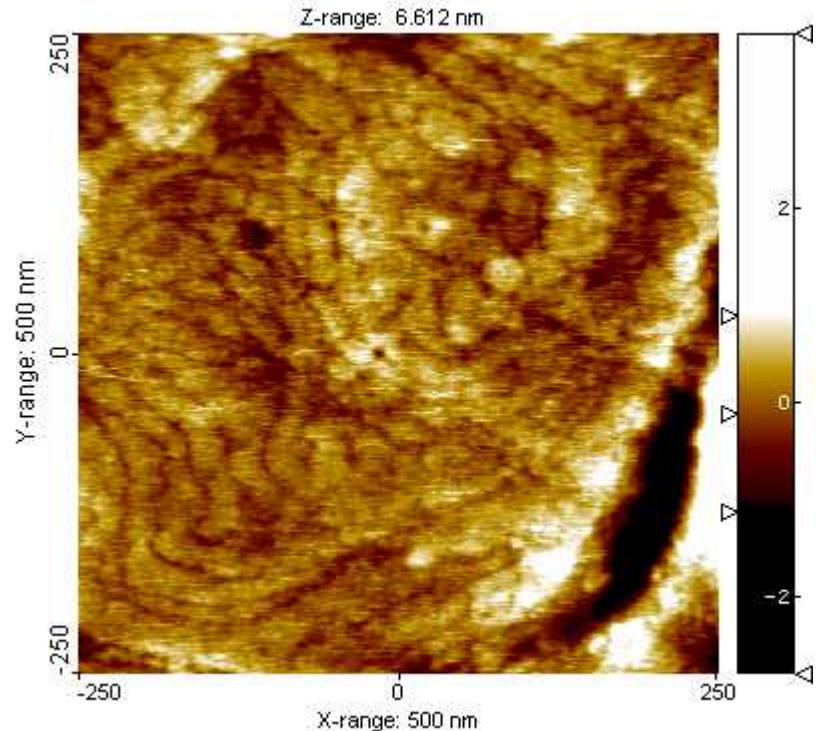
Limited by imaging mode and details of tip-surface interactions within this materials system

Imaging fidelity improves markedly on going to AM-AFM in an attractive mode

hydrated Al - 0.5 wt% Cu film in 50 mM Cl⁻, pH5.9



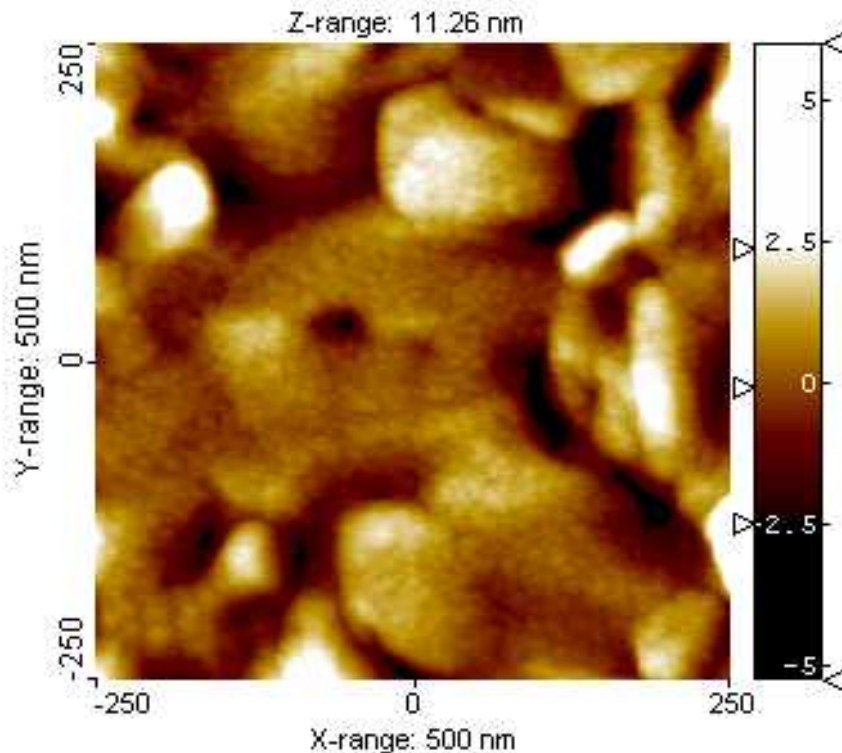
growth steps from the deposition process are evident



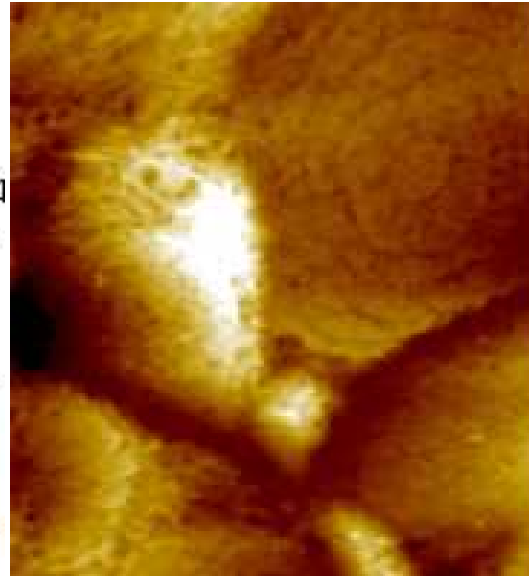
oxide platelets decorate the growth step edges

Structure is consistent with previous imaging of dry and hydrated surfaces

Type 1 Al films

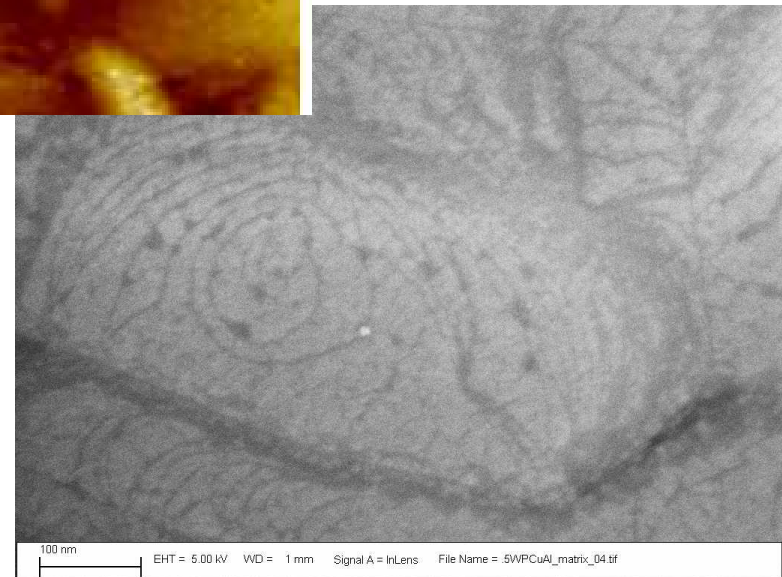


attractive mode imaging in N₂
shows morphological structure to
the oxide



imaging improves
in H₂O (1x1 μm²)

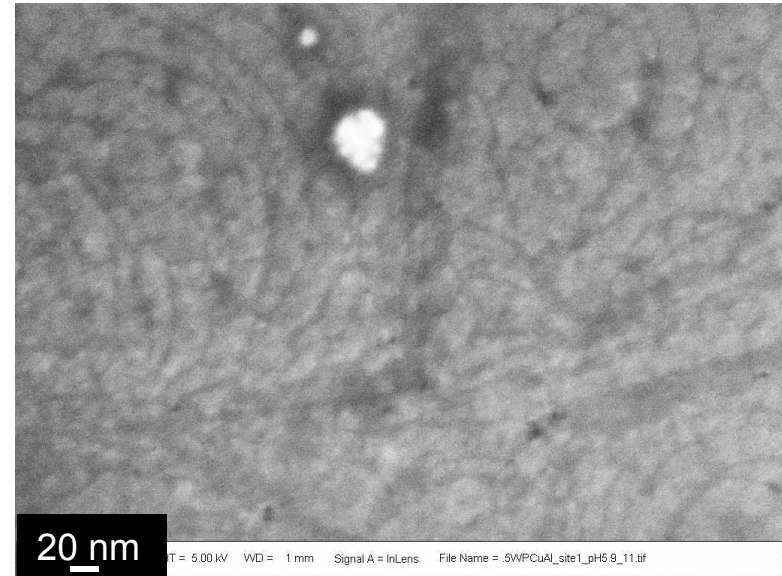
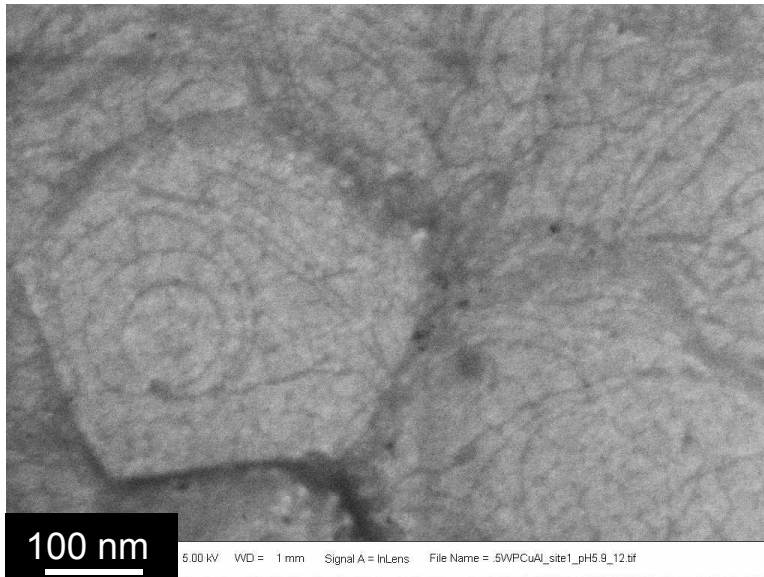
platelets with
discontinuities



Type 2 Al-Cu films

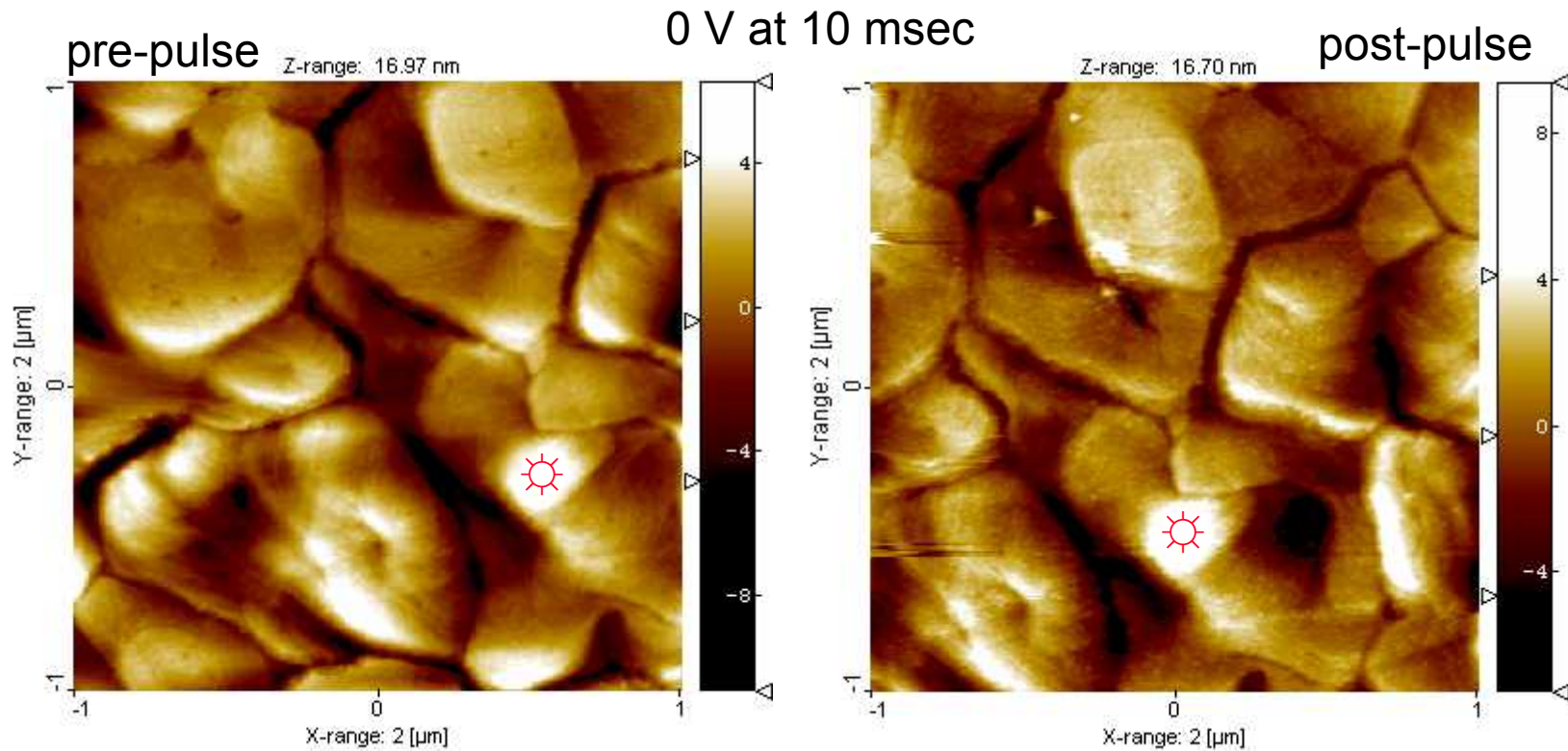
We anticipate nanopores will form in the Al-0.5 wt% Cu system with polarization

Slow rate polarization of Al-0.5 wt% Cu in 50 mM Cl⁻, pH 5.9 at 167 $\mu\text{V}\cdot\text{s}^{-1}$
ex situ SEM



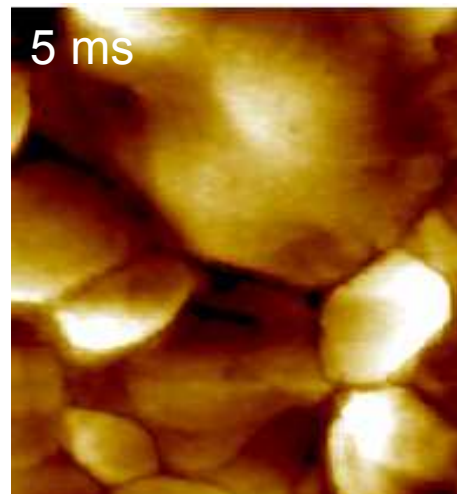
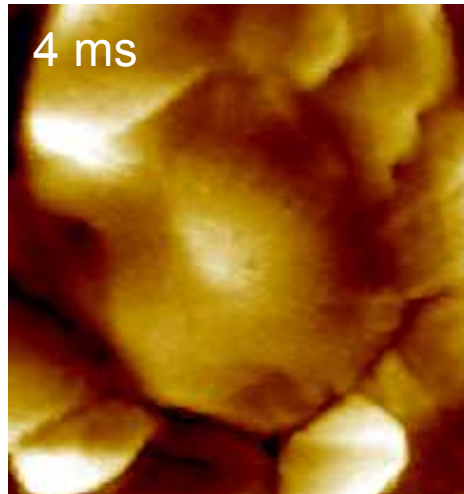
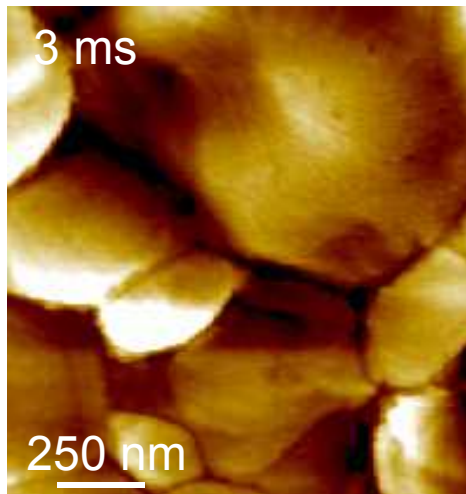
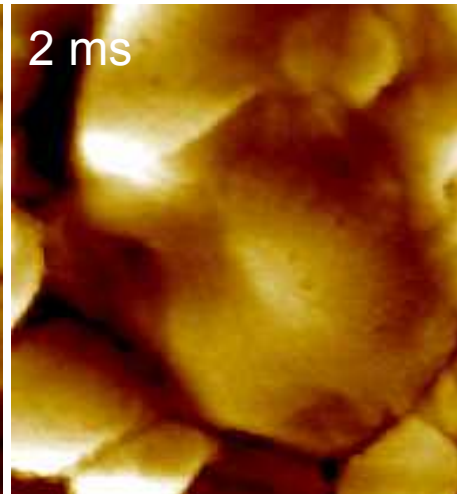
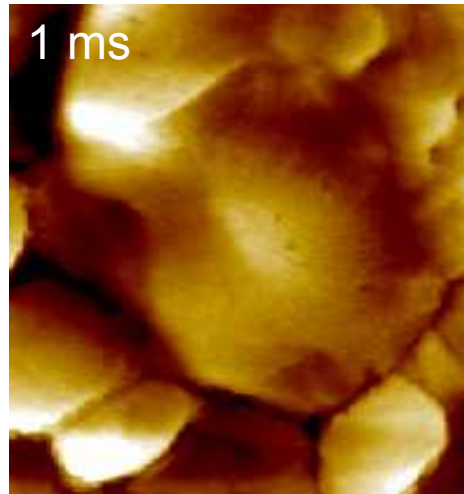
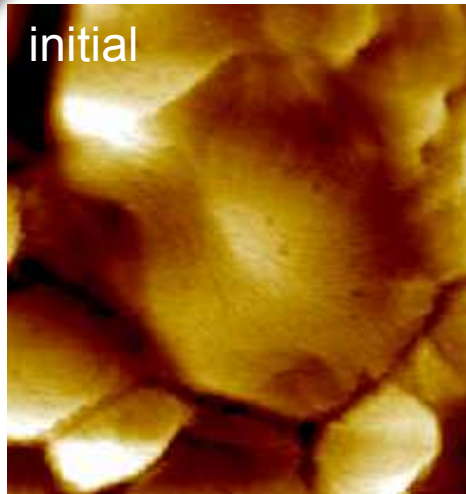
a fine pore structure appears at facet perimeters and grain boundaries

Low applied cell potentials at short times do not produce discernable impacts



tip instabilities demonstrate the difficulty of keeping tip-surface interaction attractive

Oxide platelet morphology is altered with repeated and longer potential pulses



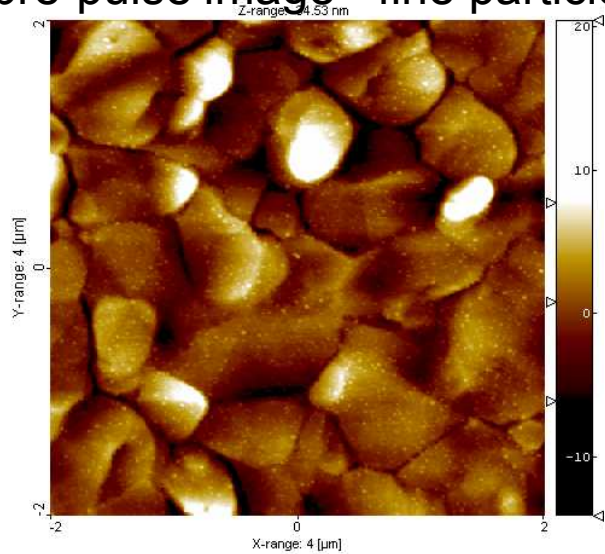
1 V tip –
sample
potential
pulse

transition
from aligned
platelet along
growth steps
to a more
nodular
structure -
induced
oxide growth

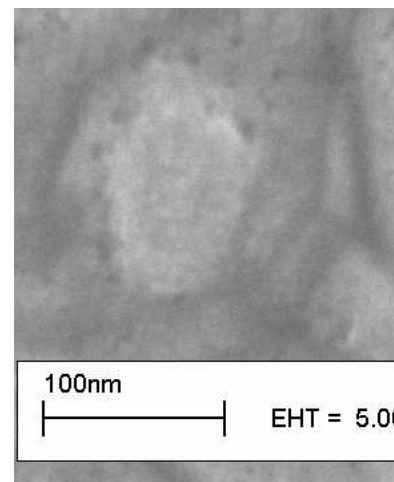
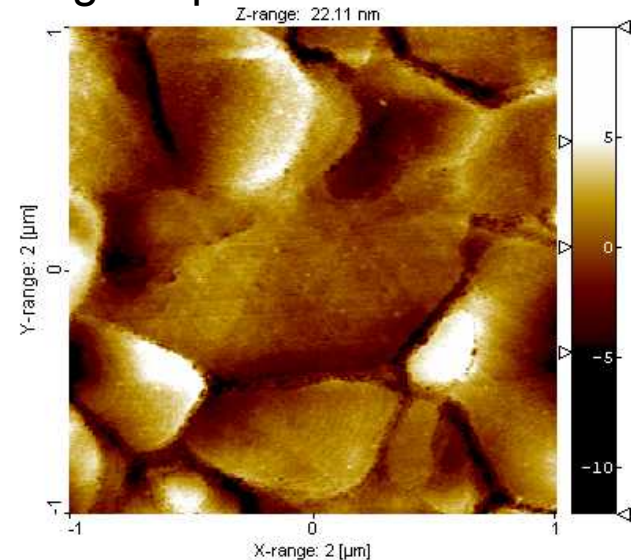
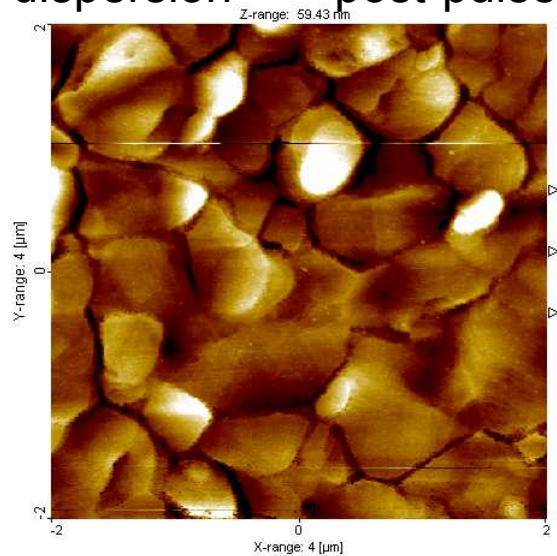
a specific degree of monitoring local site evolution appears possible

Response to a 1V, 1 sec potential pulse

pre-pulse image - fine particle dispersion



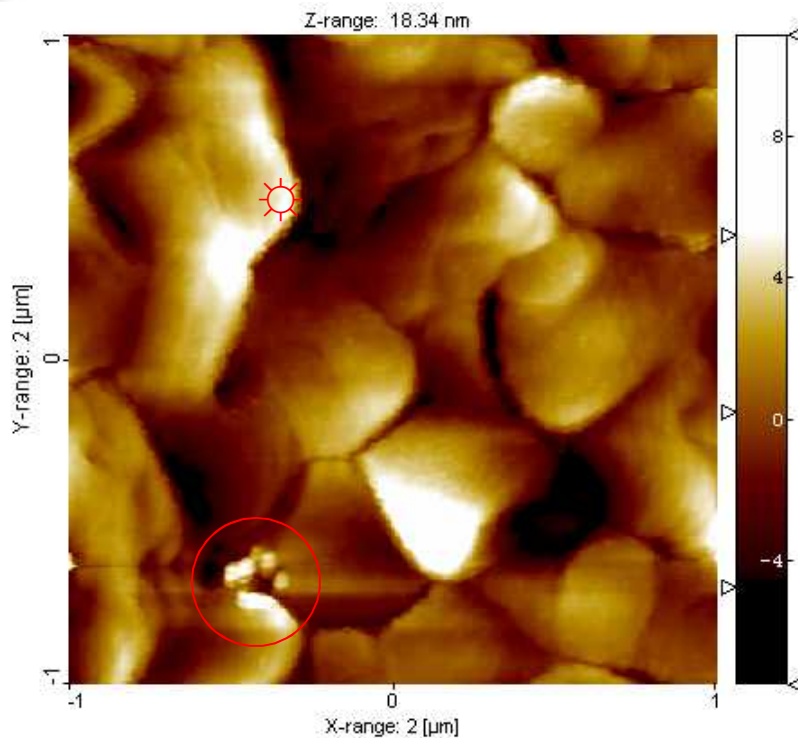
post-pulse images - particle loss



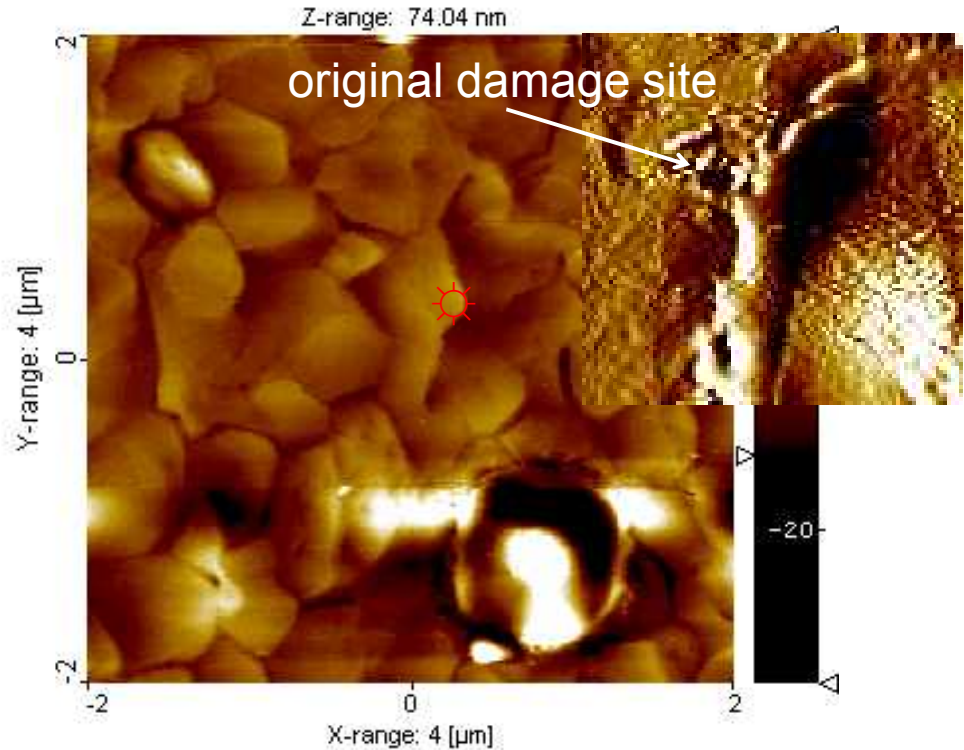
a fine pore structure appears at facet boundaries and edges

similar response to high rate current steps

Unintended tip-surface interactions create undesired effects



Excessive lever amplitude damping observed during a slow tip retraction from the surface –repulsive tip contact



Post 0 V, 1 msec pulse apparently drove the resulting pit



Conclusions

- *in situ* high fidelity imaging of the mechanically compliant passive oxide on aluminum is possible
operating in attractive mode AM-AFM is critical
- Localized anodic modification of the passive oxide is possible to monitor with *in situ* imaging
anodic dissolution confined to the lever region
nanopore formation at longer pulse times
- Current focus is to move toward higher frequency
currently capable of 14 nsec pulses
progressive sensitization of the oxide by potentiodynamic methods or repetitive pulsing